



503.30414V17

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.
Serial No.: 09/614,770
Filed: July 12, 2000
For: VACUUM PROCESSING APPARATUS AND OPERATING METHOD THEREFOR
Group: 3749
Examiner: S. Gravini
Allowed: October 13, 2000
Batch No.: T69

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AMENDMENT UNDER 37 CFR 1.312

Assistant Commissioner for Patents
Box Issue Fee
Washington, D.C. 20231

November 28, 2000

Sir:

Subsequent to issuance of the Notice of Allowance mailed October 13, 2000, please amend the above-identified application as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

- 548 D1
1. (Amended) A method of transferring a substrate, using an atmospheric loader comprising:
 - (1) a single atmospheric transferring device for carrying in and carrying out, one by one, substrates between a cassette which receives plural substrates and two lock chambers;